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H-961

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

T. HIROSE et al

Serial No. 09/774,723

Group Art Unit: 2876

Filed: February 1, 2001

Examiner: D. Lee

For: POLISHING PAD SURFACE CONDITION EVALUATION METHOD AND AN  
APPARATUS THEREOF AND A METHOD OF PRODUCING A  
SEMICONDUCTOR DEVICE

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents  
Washington, D.C. 20231

December 16, 2002


Sir:

In response to the Restriction Requirement mailed  
November 15, 2002, the Applicants elect Group II, claims 5-8  
and 16-19, without traverse.

Examination of these claims is respectfully requested.

The Commissioner is hereby authorized to charge any  
payment due, or to credit any overpayment, to Deposit Account  
No. 50-1417, including any Extension of Time Fees that may be  
necessary.

Respectfully submitted,

  
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Date: December 16, 2002

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